

Docket No.: 60188-578

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Shinichi IMAI, et al.

Serial No.:

Group Art Unit:

Filed: July 14, 2003

Examiner:

For: SYSTEM AND METHOD FOR MONITORING SEMICONDUCTOR PRODUCTION
APPARATUS

CLAIM OF PRIORITY

Mail Stop CPD
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

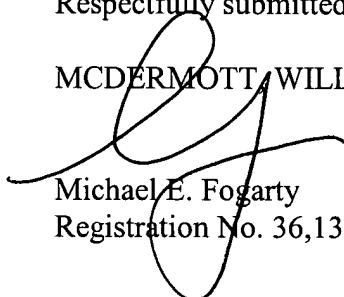
In accordance with the provisions of 35 U.S.C. 119, Applicants hereby claim the priority of:

Japanese Patent Application No. 2002-205667, filed July 15, 2002

cited in the Declaration of the present application. A certified copy will be filed in due course.

Respectfully submitted,

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